



# INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

PTO Form 1449

Attorney Docket No.

053785-5158

Application No.:

10,695,897

Applicant: Seok-Woo LEE

Filing Date: October 30, 2003

Group Art Unit: 2812-

## U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Sub Class	Filing Date

## FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Sub Class	<u>Translation</u> YES NO	
MC	2001-0052812	06/25/2001	Korea			Abstract	
MC	11-074536	03/16/1999	Japan			Abstract	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)


Examiner

*Nyana Guevara*

Date Considered

6-10-05

Examiner:

Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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February 16, 2005

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<b>INFORMATION DISCLOSURE CITATION</b> (Use several sheets if necessary)  <b>PTO Form 1449</b>	Attorney Docket No. 053785-5158	Serial No. Unassigned 10/695,897
	Applicants Seok-Woo LEE	
	Filing Date October 30, 2003	Group Unassigned 2822

<b>U.S. PATENT DOCUMENTS</b>
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*Examiner Initial	Document Number	Date	Name	Class	Sub Class	Filing Date

FOREIGN PATENT DOCUMENTS								
	Document Number	Date	Country	Class	Sub Class	Translation		
						YES	NO	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)		
MG	S. MATSUDA, et al. "Novel Corner Rounding Process For Shallow Trench Isolation Utilizing MSTs (Micro-Structure Transformation of Silicon)." IEDM Technical Digest. pp. 137-140, 1998.	

Examiner Maria Gutierrez	Date Considered 6-10-05
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